

Attorney's Docket No.: 10559-918001/P18214

Handwritten notes: "LW", a large checkmark, and a dollar sign "\$".

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Alexander Tregub et al.      Art Unit: 1773  
Serial No.: 10/799,435      Examiner: R. Zacharia  
Filed : March 12, 2004  
Assignee : Intel Corporation  
Title : PROCESS TO OPTIMIZE PROPERTIES OF POLYMER PELLICLES  
AND RESIST FOR LITHOGRAPHY APPLICATIONS

**MAIL STOP AMENDMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Applicants call attention to the attached Information Disclosure Statement and documents listed on form PTO-1449.

The documents are in the English language; hence no concise explanation is necessary per Rule 98(a)(3).

Consideration of the foregoing and enclosures plus the return of a copy of the enclosed form PTO-1449 with the Examiner's initials in the left column per MPEP 609 are earnestly solicited along with an early action on the merits.

**CERTIFICATE OF MAILING BY FIRST CLASS MAIL**

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I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

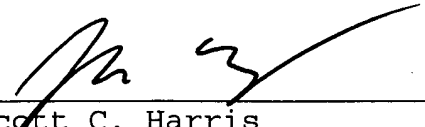
Date of Deposit August 4, 2006  
Signature [Handwritten Signature]  
Typed or Printed Name of Person Signing Certificate Carroll Allman

Handwritten number "5".

Kindly accept this Information Disclosure Statement under Rule 97(c)(2). Please apply the rule 17(p) certification fee in the amount of \$180 to Deposit Account No. 06-1050.

Respectfully submitted,

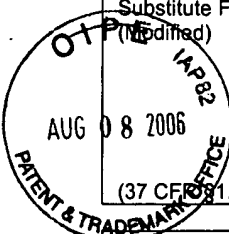
Date: August 4, 2006

  
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Scott C. Harris  
Reg. No. 32,030  
Attorney for Intel Corporation

Fish & Richardson P.C.  
USPTO Customer No. 20985  
12390 El Camino Real  
San Diego, CA 92130  
Telephone: (858) 678-5070  
Facsimile: (858) 678-5099

BY  
**JOHN F. CONROY**  
**REG. NO. 45,485**

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Substitute Form PTO-1449 (Modified)	U.S. Department of Commerce Patent and Trademark Office	Attorney's Docket No. 10559-918001	Application No. 10/799,435
<b>Information Disclosure Statement by Applicant</b> (Use several sheets if necessary) (37 CFR 1.98(b))		Applicant Alexander Tregub et al.	
		Filing Date March 12, 2004	Group Art Unit 1773

### U.S. Patent Documents

Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	AA	2001/0004508	06/2001	Shirasaki			
	AB	2001/0014375	08/2001	Tanaka			
	AC	2002/0136965	09/2002	Tsumoto et al.			
	AD	2002/0179852	12/2002	Zheng et al.			
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	AZ	6,822,731	11/2004	Laganza et al.			
	BA	6,841,312	01/2005	Kalk			

Examiner Signature	Date Considered
EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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U.S. Patent Documents							
Examiner Initial	Desig. ID	Document Number	Publication Date	Patentee	Class	Subclass	Filing Date If Appropriate
	BB	6,842,227	01/2005	Shu			
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Foreign Patent Documents or Published Foreign Patent Applications								
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							Yes	No
	BE	0 252 673	01/1988	Europe				
	BF	0 416 528	03/1991	Europe				
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	BI	0 942 325	09/1999	Europe				
	BJ	09-005982	01/1997	Japan				
	BK	2005/022259	03/2005	WIPO				

Other Documents (include Author, Title, Date, and Place of Publication)		
Examiner Initial	Desig. ID	Document
	BL	Chen, et al., "Pellicle-Induced Reticle Distortion: An Experimental Investigation", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 3546, pp. 167-172 (1998).
	BM	Cotte, et al., "Effects of Soft Pellicle Frame Curvature and Mounting Process on Pellicle-Induced Distortions in Advanced Photomasks", <i>Proc. of SPIE - The Int'l Soc. for Optical Engineering</i> , Vol. 5040, pp. 1044-1054 (2003).
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	BP	Kozeki, T., et al., "Longevity of 193nm/ArF Excimer Pellicle", Mitsui Chemicals, Inc., Pellicle Dept., pp. 1-17 (2001).
	BQ	Oshima, et al., "Chemical structure and physical properties of radiation-induced crosslinking of polytetrafluoroethylene", <i>Radiation Physics and Chemistry</i> , vol. 62, pp.39-45 (2001).
	BR	Reu, et al., "Mechanical analysis of hard pellicles for 157 nm lithography", <i>Proc. of the 2001 SPIE Symp. on Optical Microlithography XIV</i> , vol. 4346, 9 pages (2001).
	BS	Shu, et al., "Hard Pellicle Study for 157-nm Lithography", <i>Preprint, to appear in the Proceedings of Photomask Japan</i> , pp. 1-12 (2002).

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EXAMINER: Initials citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	

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**Other Documents (include Author, Title, Date, and Place of Publication)**

Examiner Initial	Desig. ID	Document
	BT	Van Krevelen, D.W., with the collaboration of P.J. Hoftyzer, <u>Properties of Polymers, Their Estimation and Correlation with Chemical Structure</u> , Elsevier Scientific Publishing Company, Amsterdam – Oxford – New York, pp. 68-73 (1976).

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